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Full length article

Step flow growth of Mn$_5$Ge$_3$ films on Ge(111) at room temperature

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ABSTRACT

The very first stages of the non-diffusive growth of Mn$_5$Ge$_3$ thin films on Ge(111) substrates are characterized by several techniques. Mn$_5$Ge$_3$ films are grown by molecular beam epitaxy using the co-deposition of Mn and Ge atoms at room temperature. XRD measurements demonstrate that the thin films are monocristalline. The evolution of the RHEED intensity during the deposition and the AFM images show a step-flow growth mode. RHEED patterns, combined with TEM images, prove that the lattice mismatch of 3.7% is accommodated by the formation of an array of interfacial dislocations and by the presence of a residual strain in the thin films. These observations are supported by the numerical calculations of the critical nucleation volumes exhibiting very similar values, in the case of a pseudomorphic growth or in the case of an accommodation of the lattice mismatch by interfacial dislocations. Furthermore, the effect Ge/Mn stoichiometric and Mn-rich fluxes on the surface morphology is examined.

1. Introduction

Since about 20 years, spintronics has brought significant advances in electronics speed, data storage and power consumption [1,2]. However a key point is still restraining the full blossoming of spintronics: the lack of ferromagnetic materials fully compatible with the mainstream silicon technology, even though a great deal of efforts has been devoted to the development of semiconductors exhibiting magnetic properties. Two families of magnetic semiconductors exist. The first one is the concentrated magnetic semiconductors (CMS), based on rare-Earth chalcogenides. But the development of these compounds is hindered by their relatively low Curie temperature (T$_C$) (the highest value reported is 117 K for EuO) and notorious difficulty in materials synthesis [3,4]. The second family is the diluted magnetic semiconductors (DMS) one. These materials are extensively studied, in particular the (Ga,Mn)As alloys with T$_C$ remaining below 200 K and the Ge$_1-y$Mn$_y$ with T$_C$ around 150 K [5,6,7,8,9].

In this context, Mn$_5$Ge$_3$ has attracted a great deal of interest, since the demonstration of its epitaxial growth as a thin film on Ge(111) substrates with a thermally sharp interface, although the lattice mismatch is 3.7% [10]. That was the sign of the potential of Mn$_5$Ge$_3$ as a ferromagnetic electrode suitable for the Si/Ge technology, in particular since the interfaces play a key role in spintronics [11]. Mn$_5$Ge$_3$ is a ferromagnetic metal with a T$_C$ of 296 K and a hexagonal crystal structure (space group P6$_3$/mmc) [12]. The T$_C$ can be increased up to 450 K by introducing carbon atoms in the octahedral interstitial site of the lattice [13,14]. The spin polarization was measured at P = 15 ± 5% and the magnetic and electrical properties of the Mn$_5$Ge$_3$ and Mn$_5$Ge$_3$C$_x$ alloys have been extensively investigated [15,16,17].

Regarding the growth processes, two methods can be employed to grow Mn$_5$Ge$_3$ thin films on Ge(111) substrates with very good structural properties, especially without threading dislocations despite the significant lattice mismatch. The solid phase epitaxy (SPE) was the first method used by Zeng et al., and it is the commonly used one [10]. It consists on the deposition of manganese on Ge(111) at room temperature, followed by an annealing at 700–720 K. The Mn$_5$Ge$_3$ phase is formed thanks to the diffusion process and the epitaxial stabilization offered by the three order symmetry of the Ge(111) surface. The main drawback of this growth process is the annealing. This step is an impairment in the control of the interface Mn$_5$Ge$_3$/Ge. On one hand, it entails a diffusion profile of Mn at the Mn$_5$Ge$_3$/Ge interface, affecting the electrical properties which is detrimental to electrical spin injection. On the other hand, such an annealing step prevents the tailoring of the Mn$_5$Ge$_3$/Ge Schottky contact by, for instance, the insertion of heavy doped Ge layers at the interface, needed to maximize the spin injection through the Schottky barrier existing at the Mn$_5$Ge$_3$/Ge contact [18].

To overcome these issues, our team developed a non-diffusive growth method by molecular beam epitaxy (MBE): it consists on the formation of the Mn$_5$Ge$_3$ thin films by stoichiometric co-deposition of both Mn and Ge on Ge(111) at room temperature. The formation of a Mn$_5$Ge$_3$ film is favourable thanks to the low interface energy between Ge(111) and Mn$_5$Ge$_3$, and to its low enthalpy of formation compare to the other
phases of the Mn-Ge phase diagram [7,19,20]. The growth at room temperature allows to create well-defined interfaces on a structural point of view but especially on an electrical account [21,22].

Using the co-deposition process, we focused on the first step of the Mn₅Ge₃ thin film growth on Ge(111) and on the interface between these two materials. In-situ RHEED intensity monitoring and ex-situ atomic force microscopy (AFM) images, taken at different deposition times and for two different ratios of the respective Mn and Ge fluxes, are combined to describe the formation and the morphology of the first nanometres of the Mn₅Ge₃ films. Transmission electron microscopy (TEM) pictures of the interface revealed the atomic organization. We compared these experimental results and a numerical calculation of the critical nucleation volume $V_c$ to determine whether the accommodation of the lattice mismatch involves a pseudomorphic growth or interfacial dislocations.

2. Experimental details

The growth method of the Mn₅Ge₃ thin films was described in an earlier paper [21]. The samples are synthesized by MBE in a ultra-high vacuum chamber with a base pressure of 2.7 × 10⁻⁸ Pa. On-axis oriented Ge(111) substrates are used and are chemically cleaned before introduction into the MBE chamber. The substrate RMS roughness measured by AFM prior to the growth is 0.52 nm, on 5 × 5 μm² field. The Ge and Mn flows of the Knudsen cells were carefully calibrated and lead to a Mn₅Ge₃ growth rate of 1 nm/min. The growth can be monitored in real time by RHEED (acceleration voltage: 30 kV) and a CCD camera fixed above the fluorescent screen allows to record the evolution of the RHEED patterns versus time of deposition. Indeed, the Mn₅Ge₃ films exhibit an easily identifiable ($\sqrt{3} \times \sqrt{3}$R30°) reconstruction RHEED pattern (see for instance inset of Fig. 2 or Fig. 1e) of ref. [23]). For some of the samples, the growth was interrupted in order to image by AFM or TEM the surface of the samples at the corresponding time (i.e. at an equivalent deposited Mn₅Ge₃ thickness $d$ of 0.4, 3.6 and 20 nm for AFM and 20 nm for TEM) to perform XRDF analysis (at $d = 20$ nm). For the AFM images, we used a Nanoscope IIIA Multimode (Digital instruments) equipped with a 10 × 10 × 2.5 μm scanner. The images were recorded in tapping mode at room temperature using silicon probes (HQ:NSC15/AL BS, Mikromasch). The curvature radius of the silicon tips was about 8 nm (supplier specification). The curvature radius of the探头 was 7.18 Å [36]. The AFM images were analyzed using the Gwyddion software [24]. TEM investigations were performed at an accelerating voltage of 300 kV on a JEOL JEM-3010 instrument with a spatial resolution of 1.7 Å. Cross-section samples were prepared with a precision ion polishing system (PIPS). XRDF measurements were done on a θ-θ diffractometer, Panalytical XPert Pro MPD (for quantitative analysis) and a on a rotating anode Rigaku RU200BH equipped with a Mar345 detector (mainly for qualitative observations). In both cases the Cu (Kα1 + Kα2) radiation was used ($λ = 0.1542$ nm). XPert HighScore software was used for peak analysis.

3. Calculation

The aim of the following calculation is to obtain a trend whether the lattice mismatch between Mn₅Ge₃ and Ge(111) gives rise to a pseudomorphic growth or to an array of interfacial dislocations, since no other accommodation mechanisms are observed. The first stages of an epitaxial growth can be assimilated to a condensation process provided that the chemical potential of the gas phase is higher than the one of the solid phase. Thermodynamics foretells a critical volume $V_c$ of the nuclei deposited on the surface above which they are stable. $V_c$ is calculated by maximizing the nucleation free enthalpy $\Delta G(V)$ of a deposited material on a substrate [25,26,27,28]. $\Delta G(V)$ can be written as follows:

$$\Delta G(V) = (E_i - \Delta V) + (\gamma_{\text{surf}} - \gamma_{\text{sub}}) S_{\text{surf}} + \gamma_{\text{dep}} S_{\text{dep}}$$

where $\Delta V$ is the elastic energy per unit of volume stored in the deposit, $\mu$ is the chemical potential difference per unit of volume of the deposit, between the gas phase and the solid phase. $\gamma_{\text{surf}}$, $\gamma_{\text{dep}}$, $\gamma_{\text{sub}}$ are the surface energies of the substrate, the deposit and the interface between the substrate and the deposit, respectively. $S_{\text{dep}}$ is the free surface of the deposit and $S_{\text{surf}}$, the area of the interface between the substrate and the deposit. From our previous work, the growth of Mn₅Ge₃ films is two dimensional, hence we limited the calculation of the critical nucleation volume $V_c$ to the bidimensional cases [21]. To simplify the problem, the nuclei are described by a cylindrical shape with a diameter $d$ and a height $h$ equal to one monolayer. Thus $\Delta G(V)$ can be rewritten:

$$\frac{\Delta G(V)}{\Delta \mu} = \left( \frac{E_i}{\Delta \mu} - 1 \right) \frac{\pi d^2}{4} h + \frac{\gamma_{\text{dep}}}{\Delta \mu} \left( \pi dh + \frac{\pi d^2}{4} (1 + a_i) \right)$$

where $a_i = (\gamma_{\text{interf}} - \gamma_{\text{sub}}) / \gamma_{\text{dep}}$. $\Delta G(V) / \Delta \mu$ exhibits a maximum for a critical diameter $d_c$:

$$d_c = \left( 1 - \frac{E_i}{\Delta \mu} - \frac{\gamma_{\text{surf}}}{\gamma_{\text{dep}}} (1 + a_i) \right)$$

This critical diameter can be written as a function of the critical volume $V_c$:

$$\frac{2 \gamma_{\text{surf}}}{\Delta \mu} = \left( 1 - \frac{E_i}{\Delta \mu} - \frac{\gamma_{\text{surf}}}{\gamma_{\text{dep}}} (1 + a_i) \right)$$

Two cases are foreseeable: a pseudomorphic growth mode of the deposit on the substrate meaning that the deposit is elastically strained on the substrate (corresponding critical volume $V^e_c$) or a growth mode where the lattice mismatch is accommodated by an array of interfacial dislocations (corresponding critical volume $V^{\text{dis}}_c$). In the first case, $E_i$ can be expressed as $E_i = \gamma_{\text{surf}} / (1 - \gamma_{\text{surf}}) R^2$, with $\gamma_{\text{surf}}$ and $\gamma_{\text{dep}}$, the Young modulus and the Poisson coefficient of the deposited materials. $m$ is the lattice mismatch between the deposit and the substrate: $m = (\Delta \gamma_{\text{dep}} - \Delta \gamma_{\text{sub}}) / \gamma_{\text{sub}}$. R takes into account the fact that the nuclei are not of infinite size in the lateral dimensions, which entails a partial relaxation, through free surfaces, of the stored elastic energy: $R = 1 - e^{-2dh/h}$. For a cylindrical shape, $k = 0.073$ and $R$ can be sensibly approximated to 1 [29]. In the second case, $E_i$ is equal to zero and the energetic cost of the formation of the dislocations has to be introduced in Eq. (3). The element $a_i$ becomes $a_i^r = a_i + a_{\text{dis}}$ where [28]:

$$a_{\text{dis}} = \frac{b \gamma_{\text{surf}}}{\gamma_{\text{dep}} (1 + a_i)} \left( \frac{1}{4 \pi} \ln \frac{h}{b} + 0.1 \right)$$

$\gamma_{\text{surf}}$ and $\gamma_{\text{sub}}$ are the Young modulus and the Poisson coefficient of the substrate, and $b$ is the Burger vector of the dislocations.

4. Results and discussion

4.1. Numerical results on the critical nucleation volumes

The numerical values of the experimental parameters needed to perform the calculations of the critical nucleation volumes $V^e_c$ and $V^{\text{dis}}_c$ are summarized in Table 1. $\Delta \mu$ was fixed at 0.5 eV. This value was chosen using ref. [30] where the authors demonstrate that a value of $\Delta \mu = 0.5$ eV around 19 corresponds to the limit between a growth mode prone to kinetic roughening and a layer-by-layer one.

Table 1

<table>
<thead>
<tr>
<th>Ge</th>
<th>Mn₅Ge₃</th>
<th>Interface</th>
</tr>
</thead>
<tbody>
<tr>
<td>Young modulus $Y$ (GPa)</td>
<td>103 [31,32,33]</td>
<td>110 [34]</td>
</tr>
<tr>
<td>Poisson’s ratio $\nu$</td>
<td>0.26 [31,32,33]</td>
<td>0.6 [35]</td>
</tr>
<tr>
<td>Surface/interface energy ($J/m^2$)</td>
<td>1.06 [35]</td>
<td>0.53 [7,19]</td>
</tr>
<tr>
<td>Burger’s vector $b$ (Å)</td>
<td>7.18 [36]</td>
<td>5 [37]</td>
</tr>
<tr>
<td>Monolayer height $h$ (Å)</td>
<td>5 [37]</td>
<td></td>
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versus V. Bottom) The color scale on the right side is

substrate via an elastically strained
via an array of interfacial dislocations

4.2. Mismatch accommodation

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exhibits values from 1.5 to 3.75 J

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Mn5Ge3

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could be simultaneously observed during the growth of the Mn5Ge3

that the two mechanisms of accommodation of the lattice mismatch

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streak patterns were still detected, allowing the measurement of the

value of the lattice parameter. The evolution of the intensity is dis-

distance between the 00 and 01 streaks, which is converted into the

RHEED. The intensity of the specular streak is recorded along with the

value of Mn5Ge3 is 0.415 nm. The fact that the RHEED pattern of

energy and of the Poisson’s ratio of the Mn5Ge3 deposit. Top figure: accom-
mmodation of the lattice mismatch between the Mn5Ge3 film and the Ge(111)

Here are the typical values of strain obtained

by ultrasonic methods [39,40,42]. Regarding the abscissa axis, the range [0.20–0.50] corresponds to typical Poisson’s coefficients observed for several families of materials [43]. The two maps are presented on Fig. 1.

Two parameters remain unknown: the surface energy γdep of the

Mn5Ge3 film and the Poisson’s ratio νdep of Mn5Ge3. We chose to draw the

maps of Vc and Vcdis versus γdep and νdep. The range of values for the

γdep axis was determined knowing that the Mn5Ge3 surface is Mn rich ter-
minated [38]. According to the literature, the Mn surface energy exhibits values from 1.5 to 3.75 J m−2 [39,40,41,42]. Regarding the abscissa axis, the range [0.20–0.50] corresponds to typical Poisson’s coefficients observed for several families of materials [43]. The two maps are presented on Fig. 1.

The two maps are very similar in terms of values reached by the critical volumes and in terms of distribution of these values as a function of γdep and νdep. From an epitaxial growth point of view, it means that the two mechanisms of accommodation of the lattice mismatch could be simultaneously observed during the growth of the Mn5Ge3 film on Ge(111), as confirmed by the following experimental results.

4.2. Mismatch accommodation

The deposition of the Mn5Ge3 thin films are followed in situ by RHEED. The intensity of the specular streak is recorded along with the distance between the 00 and 01 streaks, which is converted into the value of the lattice parameter. The evolution of the intensity is displayed on Fig. 2.

As soon as the co-deposition of Ge and Mn started, the intensity decreased significantly. Although the intensity dropped, the RHEED streak patterns were still detected, allowing the measurement of the lattice parameter all along the co-deposition. From 0 to a thickness of 4.0 nm, the lattice evolved from (0.400 ± 0.005) nm (Ge(111) surface) to (0.420 ± 0.050) nm. After a deposition of 4.0 nm, the lattice value stabilised around (0.418 ± 0.025) nm. This indicates that a slight tensile strain (0.7%) remains in the Mn5Ge3 film since the lattice bulk value of Mn5Ge3 is 0.415 nm. The fact that the RHEED pattern of

Mn5Ge3 was quickly obtained, is consistent with the small values of the critical volumes of nucleation calculated on Fig. 1. The crystallinity of the 20 nm thick Mn5Ge3/Ge(111) thin film was examined by XRD, in order to get information regarding the c-axis of the Mn5Ge3 lattice. The XRD patterns are displayed on Fig. 3.

The 2D-XRD image of Fig. 3a) is consistent with a single crystal Mn5Ge3 layer, the position of the diffraction spots being in good agreement with the reflections (as indicated in the image) mentioned in the reference file of Mn5Ge3 (ICSD-01-089-4887). On Fig. 3b), the θ-θ measurements show that only the diffraction peaks corresponding to the 002 and 004 reflections were detected. This indicates a monocrystalline Mn5Ge3 thin film with the c-axis normal to the surface of the substrate, in agreement with the 2D-XRD data. Fitting these XRD data with the profile fitting software X’Pert HighScore, the interplanar distance d_{003} is measured at (0.5035 ± 0.0001) nm. This value indicates a compressive strain of − (0.5 ± 0.1)% of the Mn5Ge3 lattice, along the c-axis. The full width at half maximum (FWHM) of the diffraction peaks of Mn5Ge3 is 0.51° (the instrumental width evaluated with the 111 reflection of the Ge substrate is 0.03°). Considering that the broadening of the diffraction peaks arose from the low thickness of the film, we apply the Scherrer equation to obtain a minimal thickness value of the Mn5Ge3 film of 17 nm, which is consistent with the 20 nm thick film planned with the deposition fluxes [44]. The values of strain obtained with the RHEED and XRD characterizations have to be compared to the 3.7% lattice mismatch between Ge(111) and the bulk Mn5Ge3: the Mn5Ge3 thin film is almost relaxed. To go further in the description of the Mn5Ge3/Ge(111) interface, cross-sectional TEM images of the interface have been taken (Fig. 4).

A periodical intensity contrast can be observed on the top image, with an occurrence every 16 nm along the [010] direction of the Mn5Ge3 film. It corresponds to an array of dislocations spaced of a distance corresponding to 24 unit cells. This arrangement entails a relaxation of the thin film with a slight remaining tensile strain of 0.65%, in good agreement with the RHEED measurements. The bottom image shows an enlargement focussed on a dislocation: a stacking fault can be seen at the centre of the white dotted ellipse. Interfacial dislocations along the Ge(111)/Mn5Ge3 interface have also been observed in the

Fig. 1. Maps of the critical volume of nucleation as a function of the surface energy and of the Poisson’s ratio of the Mn5Ge3 deposit. Top figure: accommodation of the lattice mismatch between the Mn5Ge3 film and the Ge(111) substrate via an elastically strained film (Vc). Bottom figure: accommodation via an array of interfacial dislocations (Vcdis). The color scale on the right side is in nm³.

Fig. 2. Typical evolution of the intensity of the 00 streak of the RHEED pattern taken along the azimuth [210] of the typical Mn5Ge3(001) (\textit{\textgamma} \times \textit{\textgamma}R30°) surface. The white dotted rectangle on the pattern indicates the area used to record the intensity. The white double arrow shows the distance between the streaks used to calculate the value of the lattice parameter of the Mn5Ge3(001) plan.
The evolution of the specular intensities is the same for both growth conditions. The persistent streaky RHEED patterns along with the quickly damped intensities and one discernible oscillation are commonly attributed to a one-dimensional step-flow growth mode [47,48]. This implies a quite high surface mobility of the adatoms. The difference between the stoichiometric and Mn-rich conditions lies in the background intensity, which is higher in the case of the Mn-rich growth. This can be linked to a bigger surface roughness of the thin film, maybe due to the increase of Mn adatoms. To confirm these statements related to the RHEED observations, AFM images have been taken at different film thicknesses on as-grown samples. Panels a) and g) in Fig. 5 (resp. d) and h)) show the surface morphology of 0.4 and 20 nm thick Mn₅Ge₃ films grown with stoichiometric (resp. Mn-rich) condition.

On Fig. 5a) and g), corresponding to thin films grown under stoichiometric fluxes, terraces with non-uniform length are clearly visible, and the surface morphology exhibits a slight fingers like pattern. This confirms the step-flow growth mode and points out a meandering instability which may arise from different surface diffusion lengths and an asymmetric attachment to the steps of the Ge and Mn adatoms as described in refs. [49] and [50] and observed in the case of plasma-assisted MBE growth of GaN layers on different kinds of GaN substrates [51]. The height and the maximum length of these terraces have been measured on a 2 × 2 μm² scans and were evaluated to (0.40 ± 0.08) nm and (140 ± 10) nm, respectively (cf. AFM profile Fig. 5b)). The terrace height is closed to the thickness of one monolayer of Mn₅Ge₃ along the c-axis of the lattice: 0.5 nm [37]. The RMS roughness for both films thicknesses is 0.76 nm. Hexagonal pits are present for both thicknesses (No pits are observed on the Ge(111) substrates surfaces before the growth). The hexagonal shape is attributed to the hexagonal lattice of Mn₅Ge₃. The pits can be classified in two groups (labelled 1 and 2 in the AFM images) according to their location on the surface and their profile (Fig. 6).

The first group consists of pits (labelled 1 on AFM images from Fig. 5) with a depth of tens of nanometres. The second group contains pits with a depth of only a few nanometres and with a flat bottom. Regarding the films growth under a Mn-rich co-deposition, the surface morphology appears more disturbed with lot of deep hexagonal holes, and still exhibits a fingers like morphology but with smaller features than the stoichiometric co-deposition case. Examining carefully the AFM 2 × 2 μm scans, terraces are visible with a height of (0.45 ± 0.05) nm, which is still consistent with the step-flow growth detected by RHEED. The RMS roughness is around 2.2 nm. To understand the evolution of the surface morphology, we have analyzed the distribution

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**Fig. 3.** a) 2D-XRD pattern of a 20 nm thick Mn₅Ge₃ thin film. The signal of the Ge substrate has been subtracted. The angle between the incident X-ray beam and the sample surface (ω angle) varied from 15 to 20° during the acquisition. b) XRD pattern of the 20 nm thick Mn₅Ge₃ thin film. The diffraction peaks correspond to the 002 and 004 reflections of Mn₅Ge₃. The insert displays the peaks corresponding to the 111 reflection of Ge substrate (CuKα1, CuKα2), the Ge signal was attenuated by a factor 85, in order to avoid the damage of the detector.

**Fig. 4.** Top image: TEM image of a cross section of Mn₅Ge₃ film. The periodical contrast of the intensity at the interface indicates the presence of interfacial dislocations every 16 nm. Bottom image: zoom on a dislocation from the top image.
of the pits depth versus the thickness $d$ of the thin films (Fig. 7).

The distributions of the depths evolve with $d$: at the very beginning of the deposit, the majority of the pits exhibits a depth in the sampling interval of $[-0.5; -1.5]$ nm i.e. in the range of the deposited thickness. Some holes already have a deeper depth around $-10$ nm. For $d = 3.6$ nm, the distribution is bimodal: one part of the holes sampling presents a depth centred in the interval $[-3.5; -4.5]$ nm, and the second part consists of holes with a depth between $-40$ and $-50$ nm. As the deposition time increases, the depth distribution becomes once again mono-modal: the deepest pits disappear, and the majority of the depths is in the interval $[-0.5; -1.0]$ nm for $d = 20$ nm: the pits may be filled during the growth. At this thickness, the pits density is $12.5 \mu m^{-2}$ compared to $0.3 \mu m^{-2}$ in the case of the stoichiometric co-deposition.

Such pits were also observed in the case of GaN growth by MBE or plasma assisted MBE under Ga rich growth conditions [48,51,52]. The pits of group 2 have been described as vacancy islands caused by the self-crossing of the meandering steps, and which are not filled by the growth thereafter. These pits pin the steps and entail the fingers like morphology of the surface. Regarding the deeper holes of group 1, it seems unlikely that they can be related to dislocations or impurities: no dislocations (except interfacial ones) are observed in the TEM images of the Mn$_5$Ge$_3$ thin films, and the pits densities should be almost the same for both growth conditions if impurities were involved. So the group 1 may be also characteristic of the growth mode. This conclusion meets

Fig. 6. Profiles from the hexagonal pits labelled 1 and 2 on the AFM images displayed on Fig. 5. Profile 1 corresponds to deep pits seemingly coming from the growth process and profile 2 corresponds to vacancy islands caused by self-crossing steps.

Fig. 7. Distributions of the depth of the holes from the AFM scans performed at film thickness $d$ of 0.4, 3.6, 6 and 20 nm (not shown here). The number of pits is expressed in percentage of all the counted holes on each AFM images. The RMS roughness is reported for each deposition thickness.
the one drawn by Chêze et al. regarding the growth of GaN films by plasma assisted MBE [51]. Another argument in favour of a characteristic of the growth mode comes from the other growth process of the MnGe film, the SPE. Indeed, in the case of the SPE growth of manganese silicides and germanides, deep holes are also observed in the early stages of the thin films [37,53]. Hirvonen Grytzelius et al. have shown that an almost fully covering MnGe film is obtained only after a deposition of 32 monolayers of Mn, corresponding to a MnGe thickness of 50 nm. The holes are thought to play two main roles: local areas of strain relaxation of the thin films and complementary Ge sources for the formation of the MnGe phase. This last point is consistent with our experiments where the pits density is higher in the case of a Mn-rich co-deposition. It means that to form the MnGe phase, additional Ge atoms are drawn off in the substrate, thus creating deep holes.

5. Conclusion

A study of the early stages of the non-diffusive growth of MnGe thin film on Ge(111) substrate has been carried out. This system exhibits a significant lattice mismatch of 3.7%. XRD measurements demonstrate that the thin film is monocrystalline and, combined with RHEED diffraction patterns analysis, that the MnGe lattice is slightly strained. TEM images show the presence of interfacial dislocations at the MnGe/Ge interface, every 16 nm along the [010] direction of the MnGe film. Thus, the lattice mismatch is accommodated by two phenomena: a pseudomorphic growth and interfacial dislocations. Numerical calculations support these observations: the critical nucleation volume calculated for both the case of a pseudomorphic growth and the case of an accommodation of the lattice mismatch by an array of dislocations, are very similar in values. AFM images taken at different deposition times and the evolution of the specular RHEED intensity, both recorded in stoichiometric and Mn-rich co-deposition, show that the MnGe films grow according to a step-flow mode, with a meandering instability.

Acknowledgments

The authors would like to thank D Chaudanson from the electron microscopy service of the CINaM for his support regarding the TEM images and C Coudreau for the technical support on the MBE growth set-up. Appendix A. Supplementary data

Supplementary data to this article can be found online at https://doi.org/10.1016/j.apusc.2019.01.164.

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Appendix A. Supplementary data

Supplementary data to this article can be found online at https://doi.org/10.1016/j.apusc.2019.01.164.

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